

Special Issue

Advanced MEMS/NEMS Technology

Message from the Guest Editors

The 13th International Conference on Nano/Micro Engineered and Molecular Systems (NEMS) will be held 22–26 April, 2018, at the Grand Hyatt, Singapore. NEMS is a premier conference series sponsored by the IEEE Nanotechnology Council, focusing on the promotion of advanced research areas related to MEMS, nanotechnology, and molecular technology.

Micromachines is the leading journal in the MEMS and NEMS fields. We want to consolidate original research papers and comprehensive review articles in this Special Issue. We welcome manuscripts on the following topics:

- Micro/Nanomachines
- Optical MEMS and Nanophotonics
- RF MEMS, Resonators and Oscillators
- Ultrasound MEMS (pMUT and cMUT)
- Energy Harvesting Technology
- BioMEMS and Biomedical Devices
- Neuroprosthetics and Implanted Devices
- Micro/Nanofluidics
- Soft materials and robotics
- Chemical Sensors/Gas Sensors/Sensors for environmental Monitoring
- Sensor Network/IoT

Guest Editors

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Deadline for manuscript submissions

closed (20 November 2018)



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About the Journal

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

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